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്ດ\ IN THE UNITED STATES PATENT AND TRADEMARK OFFICE		
JUN 1 3 2003 🌣 Application Serial No		09/905,320
TADEMATOR Date	CEIVED	
AssigneeGroup Art Unit	TO 19 2003	Micron Technology, Inc.
Examiner	1.700	Eric B. Fuller MI22-1657
Title: Chemical Vapor Titanate Comprisi	Deposition Methods ing Dielectric Layers, I	of Forming Barium Strontium Including Such Layers Having a ontium Within the Layer

RESPONSE TO FEBRUARY 13, 2003 OFFICE ACTION

To:

Commissioner for Patents

Washington, D.C. 20231

VIA EXPRESS MAIL

From:

Mark Matkin (Tel. 509-624-276; Fax 509-838-3424)

Wells St. John P.S.

601 West First Avenue, Stite 1300

Spokane, WA 99201/3828

Responsive to the Office Action dated February 13, 2003, Applicant

amends and remarks as follows:

<u>AMENDMENTS</u>